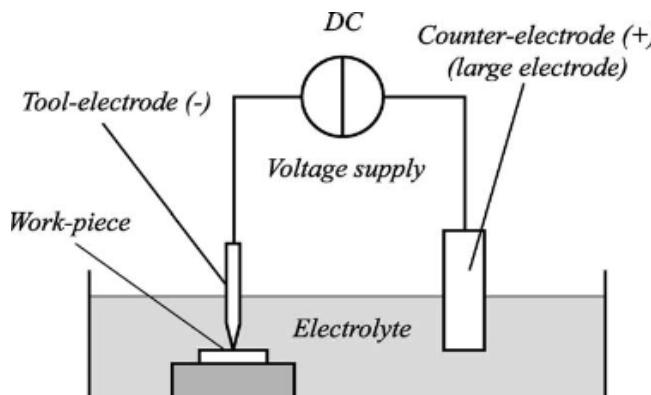


# SACE Microfactory

## What is SACE?

Spark assisted chemical engraving allows for 3 dimensional engraving in non-conductive structures. A critical voltage applied between the anode and cathode causes a high temperature coalesced vapour film to form, etching the test wafer.



General SACE diagram [1]

[1] Wuthrich R.; Fascio, V., 2005, Machining of non-conductive materials using electrochemical discharge phenomenon—an overview, *Int. J. Mach. Tools Manuf.*, 45, 1095–108

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## Objectives

Improve existing SACE microfactory safety and machining quality by:

- Protecting surrounding environment from corrosive sodium hydroxide vapour and splatter
- Controlling electrolyte level above glass wafer
- Maintaining local electrolyte temperature
- Adding rotational component to etching tool

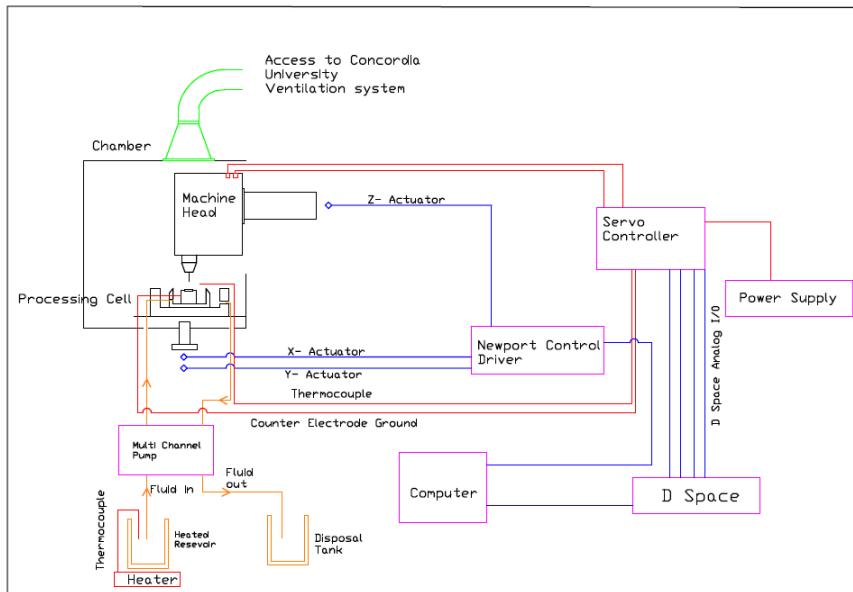


Natural Sciences and Engineering  
Research Council of Canada

# SACE Microfactory

Team # 11

The upgraded SACE allows for:



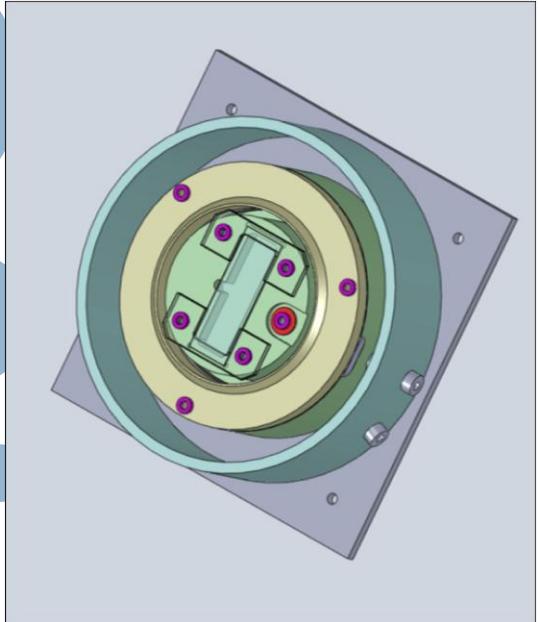
Schematic of SACE System

- Protection of surrounding equipment and personnel
- Relative x, y, z-motion, and tool rotation
- Known variable electrolyte height above glass wafer
- Monitored electrolyte temperature
- Controllable electrolyte flow rate via manual peristaltic pump
- Ease of maintenance and disassembly
- Reduced maintenance and replacement cost

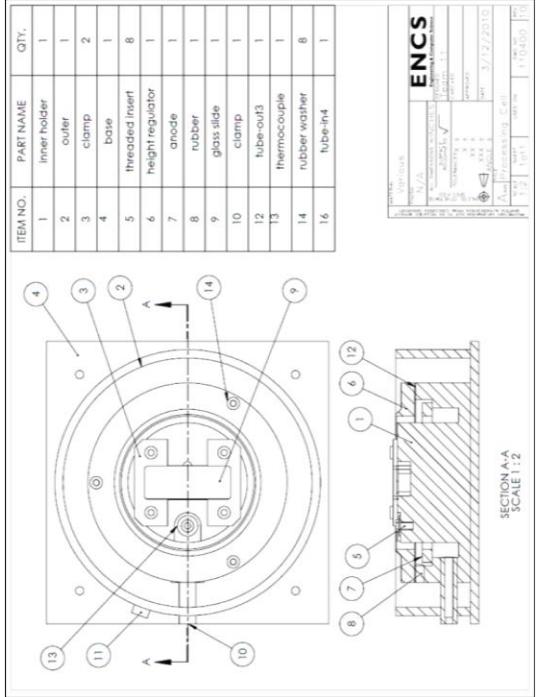
# SACE Microfactory

## Processing Cell

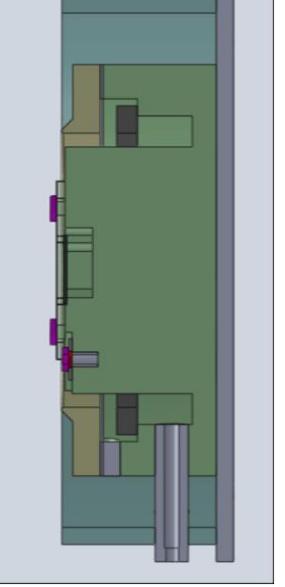
Team #11



Isometric View of Processing Cell

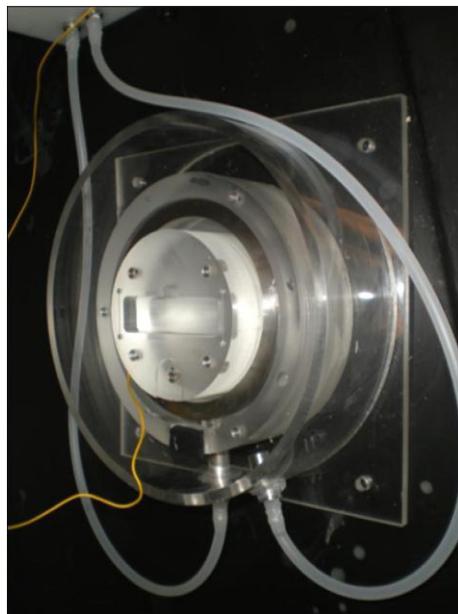


Components of Processing Cell



Cross Sectional View of Processing Cell

- Features of Processing Cell**
- composed of corrosion resistant cast acrylic and 300 series stainless steel
  - contains secured glass test section
  - slot for easy test section removal
  - allows for electrolyte intake and evacuation via manually controlled dual head peristaltic pump
  - removable barbed fittings and height regulator for ease of maintenance
  - allows for temperature reading in the vicinity of glass wafer, as fluid temperature affects machining quality
  - adjustable fluid levels above test section, as optimal fluid level is currently being researched
  - prevents accidental cathode (tool) and anode contact
  - stainless steel threaded inserts used to maintain integrity of threads
  - mounted on x and y actuators to allow for relative motion with etching tool



Assembled Processing Cell